

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Park et al.

Confirmation No.: 5520

Serial No.: 10/828,596

Group Art Unit: 2811

Filed: April 21, 2004

Examiner: Ori Nadav

For: METHODS OF FORMING METAL THIN FILMS, LANTHANUM OXIDE FILMS
AND HIGH DIELECTRIC FILMS FOR SEMICONDUCTOR DEVICES USING
ATOMIC LAYER DEPOSITION

Date: March 20, 2009

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

**AMENDMENT AND RESPONSE TO
OFFICE ACTION DATED DECEMBER 23, 2008**

Sir:

The present Amendment is provided to address the issues raised in the Office Action dated December 23, 2008.

It is not believed that any fee(s), including fees for additional claims, are required, beyond those that may otherwise be provided for in documents accompanying this submission. In the event, however, that any requests, petitions or extensions of time for the accompanying response are required to prevent abandonment of this application, Applicants submit that such an extension is also hereby petitioned for under 37 C.F.R. §1.136(a) and/or a request be granted pursuant to 37 C.F.R. §1.114. Any additional fees believed to be due in connection with this submission may be charged to our Deposit Account No. 50-0220, or any overpayment may be credited to the same.

Amendments to the Claims begin on page 2 of this document.

Remarks begin on page 13 of this document.